



ABSTRACT

BI A method of manufacturing a thin film magnetic head. The method includes forming, near a pole portion: a first magnetic layer supported by a base substrate; a first insulating layer on the first magnetic layer with an end edge which forms a reference position for an air bearing surface; a gap layer on the pole portion of the first magnetic layer and the first insulation layer; a second magnetic layer that extends to a region beyond the pole portion; a thin film coil isolated by a second insulation layer located above the first insulation layer; a third magnetic layer on the second insulation layer. The air bearing surface is formed by grinding in part an end face of the pole portion of the first magnetic layer and an end face of the pole portion of the second magnetic layer and the gap layer placed therebetween.

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